



Reliability Flagship Projects in NoE PATENT-DfMm

Ingrid De Wolf, IMEC

Nov-06

«Design for Micro & Nano Manufacture (NoE PATENT-DfMm)»

Network of Excellence funded by the European Commission (EC FP6: IST, Unit C2, Contract 507255)

- How to test reliability
 - Stress based testing vs knowledge/application driven testing
 - Test structures
 - Understanding failure mechanisms (physics of failure)
 - Networking required

- ❑ RELMETH (Marius Bazu, IMT)
- ❑ VIBSHOCT (Khiem Trieu, IMS: Ingrid De Wolf, IMEC)
- ❑ HUMIDITY (Claude Pellet, IXL)
- ❑ ACCELEROMETER (Alan Brown, QinetiQ)

Reliability flagship management:
Orla Slattery, Tyndall



RELMETH

„Methodology for accelerated testing and reliability analysis of MEMS”

Marius Bazu, IMT



QinetiQ



DIPARTIMENTO DI
INGEGNERIA STRUTTURALE



LANCASTER
UNIVERSITY



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□ Focus on ALT:

accelerated lifetime testing

(stress factors: power cycling, vibration, humid temperature cycling, temperatures, etc.)

Old scientist



□ Two 'kinds' of ALT:

- Qualitative testing: to identify design weaknesses (Accelerated Stress Testing – AST)
- Quantitative testing: to quantify reliability parameters ((Q)ALT)

□ Purpose:

To set-up a one-stop-shop for accelerated testing and reliability analysis of MEMS.

Two sub-projects:

SP1: Comparing Patent-DfMM knowledge with the state of the art in accelerated tests & reliability analysis and identifying missing elements (IMT, POLIMI, BUTE, IMS, LIRMM, ULAN, HWU, QinetiQ)

SP2: Performing (new) accelerated tests & reliability analyses on MEMS devices supplied by industry (IMT, POLIMI, BUTE, IMS, CSL, LIRMM, ULAN, HWU)

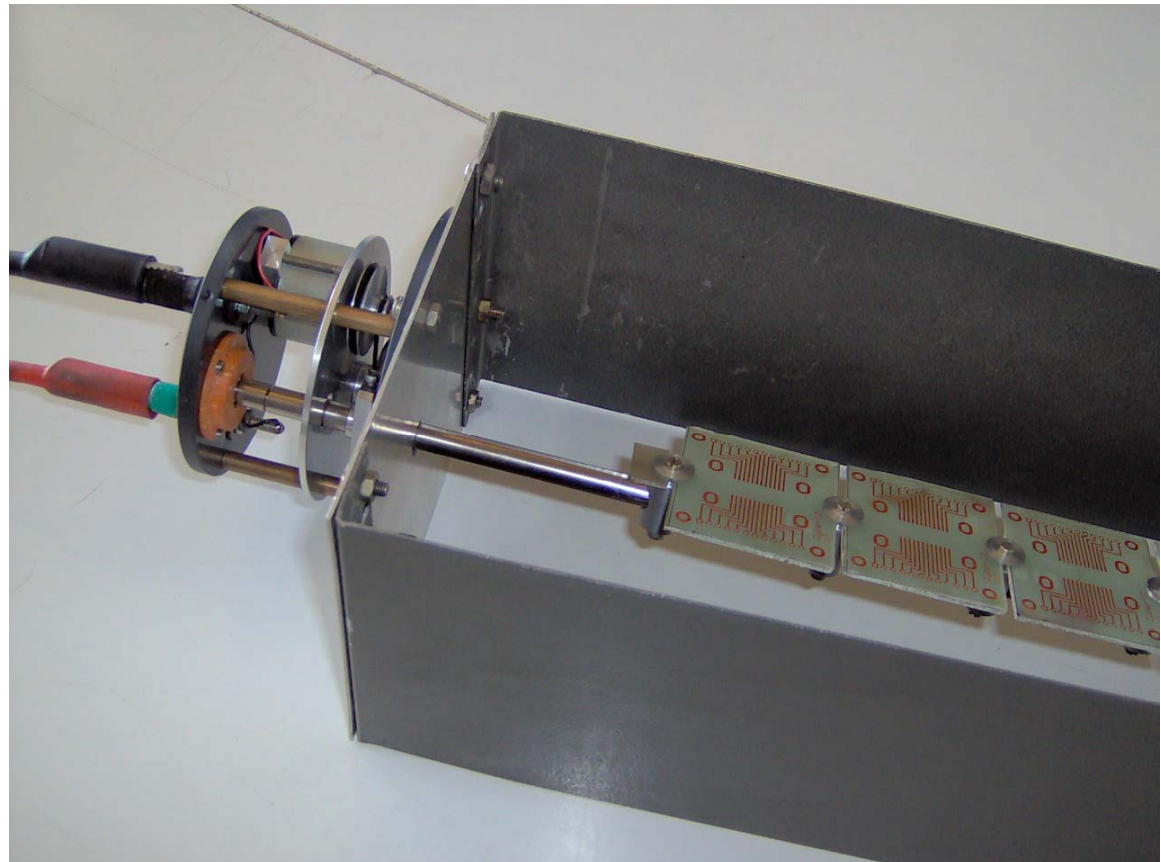
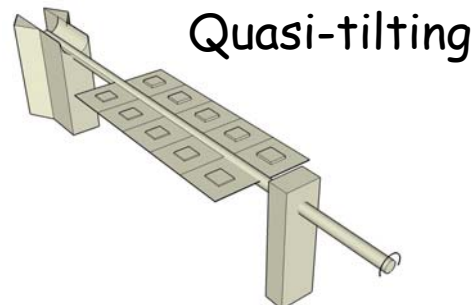
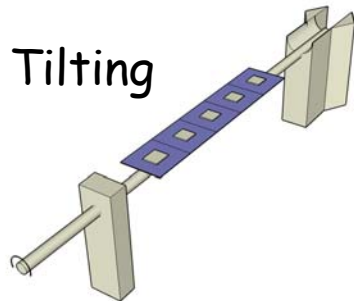
Devices from ST and from QinetiQ

- The significant acceleration factors must be chosen depending on the main application of the tested MEMS (accelerometer):
 - Mechanical + thermal stress
 - Mechanical stress: shock, acceleration, vibration, tilt
 - Thermal stress: temperature, thermal cycling
 - Vibration: appropriated for MEMS with moving parts
 - Tilting: used for transportation (avionics, auto, railways, etc.)
- The test plan will simulate:
 - an environment composed by **vibration and temperature**
 - the use of accelerometers in transportation: **tilting + temperature**



Example of a (new, application driven) ALT test: Tilting + Temperature

Mechanical stimulus –
(Quasi)tilting



- Life testing results on the accelerometers from ST Microelectronics
- A methodology for executing Accelerated Life Testing in the frame of Patent-DfMM (procedures, links, etc.)
- A study on the necessary projects for covering all the aspects of Reliability Analysis by Accelerated Testing
- A course on Reliability Analysis by Accelerated Testing



VIBshockT

*Holistic Reliability Engineering for MEMS
in harsh conditions*

Khiem Trieu, IMS / Ingrid De Wolf, IMEC

Partners: IMS, IMEC, CSL, Polimi, Tyndall, BUTE, HWU, WUT, IMT, IZM

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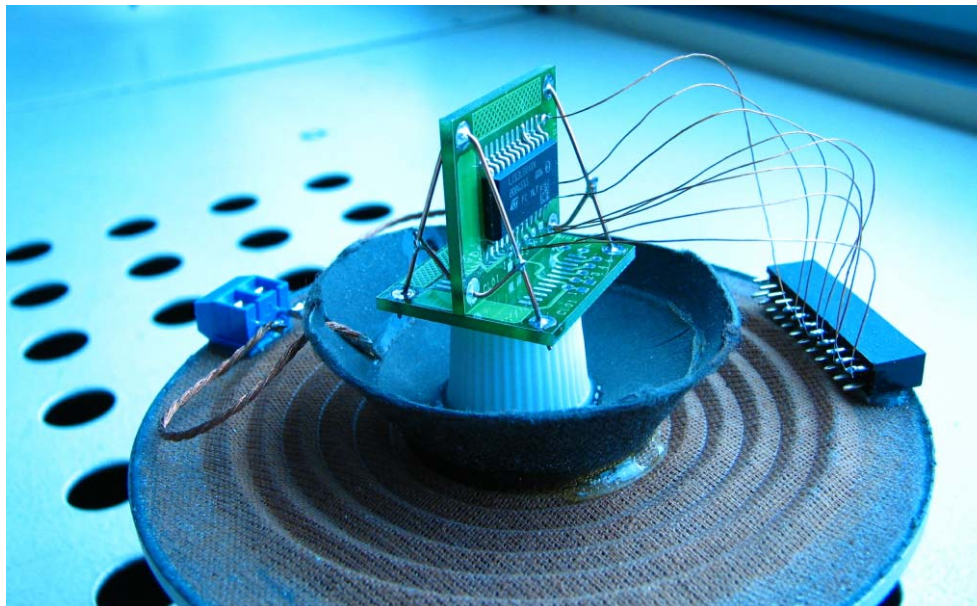
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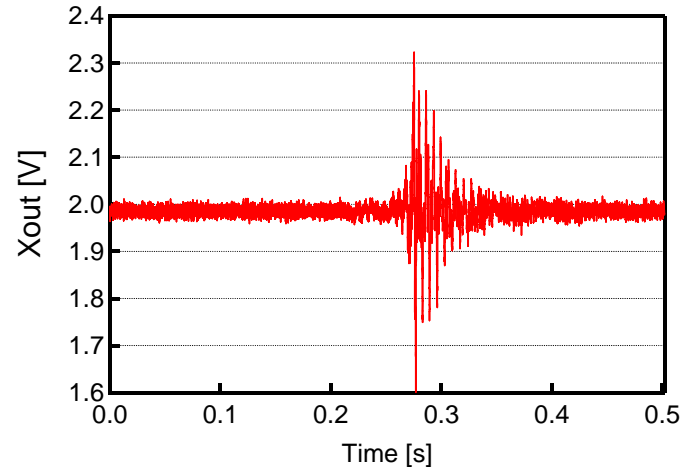
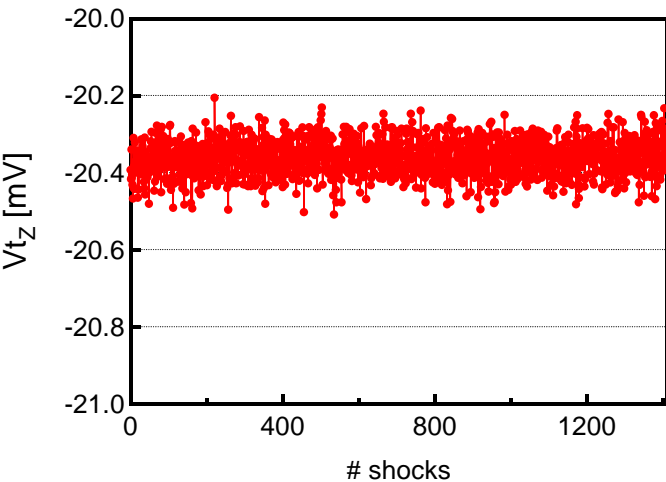
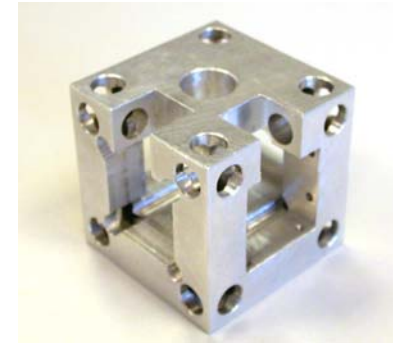
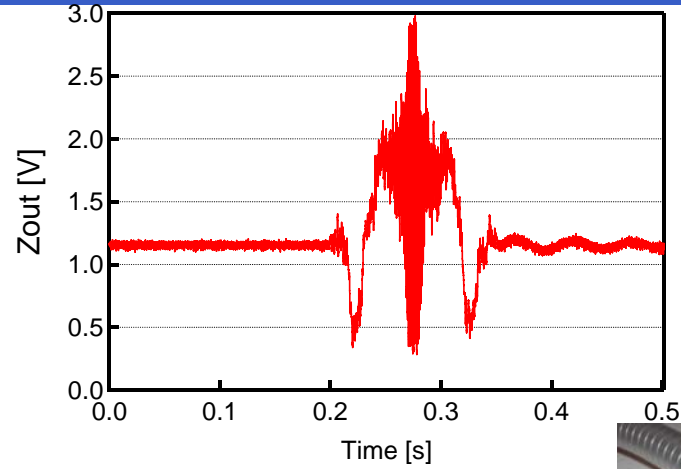
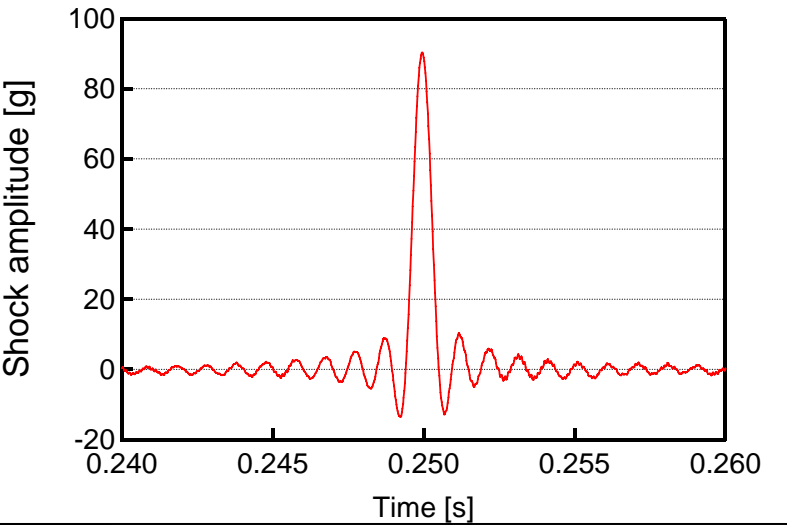
Network of Excellence funded by the European Commission (EC FP6: IST, Unit C2, Contract 507255)

- Holistic Reliability Engineering for MEMS in harsh conditions
- **Goal:** Reliability testing and experimental and modeling analysis of MEMS devices (MEMS + package) in harsh conditions (vibration, shock, temperature).
- Perform ALT tests under standard conditions (T, P, shock,...) and compare with results under 'extreme' conditions
- Verification + prediction by modeling
- Devices from ST and from Qinetiq

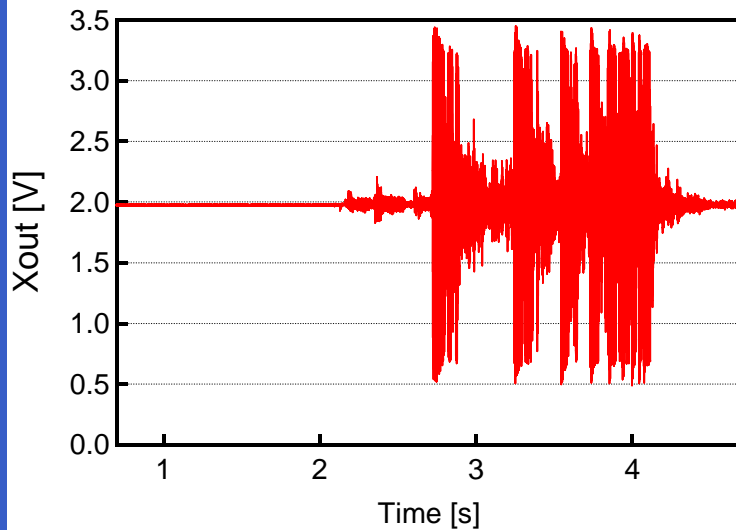
MIL-STD-883F-2005.2 vibration fatigue test method

Standard tests (Bute and IMT):
no failures observed





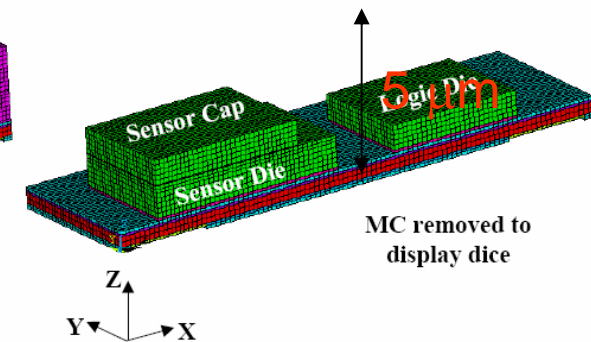
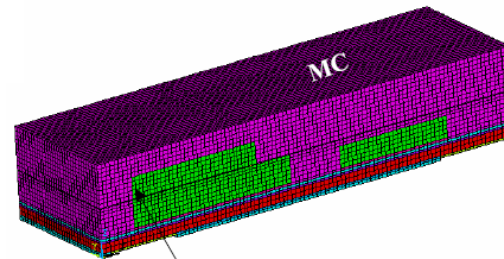
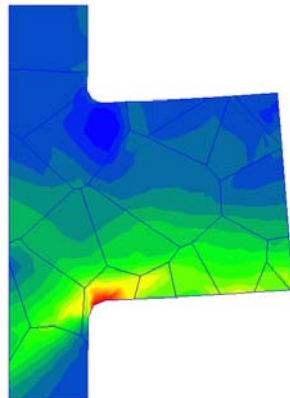
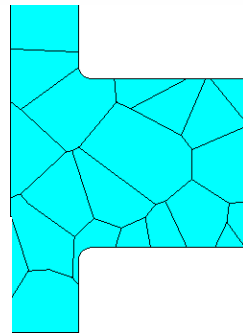
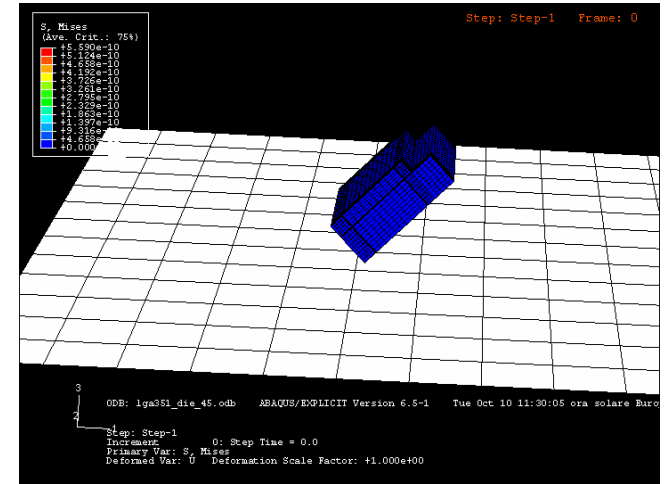
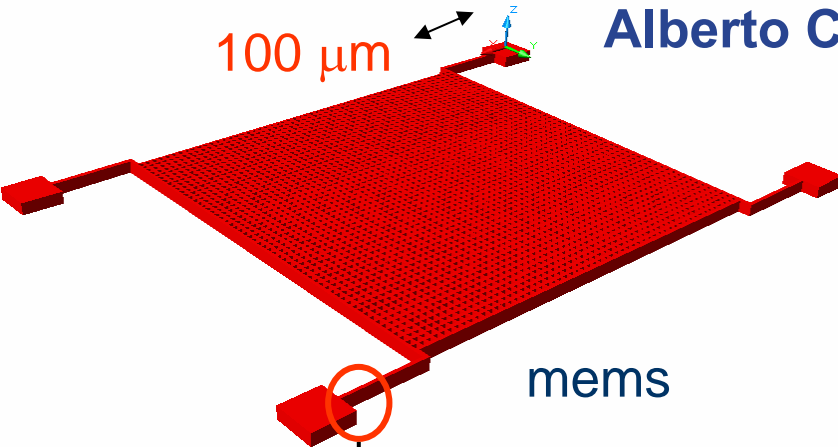
No failure (IMEC)



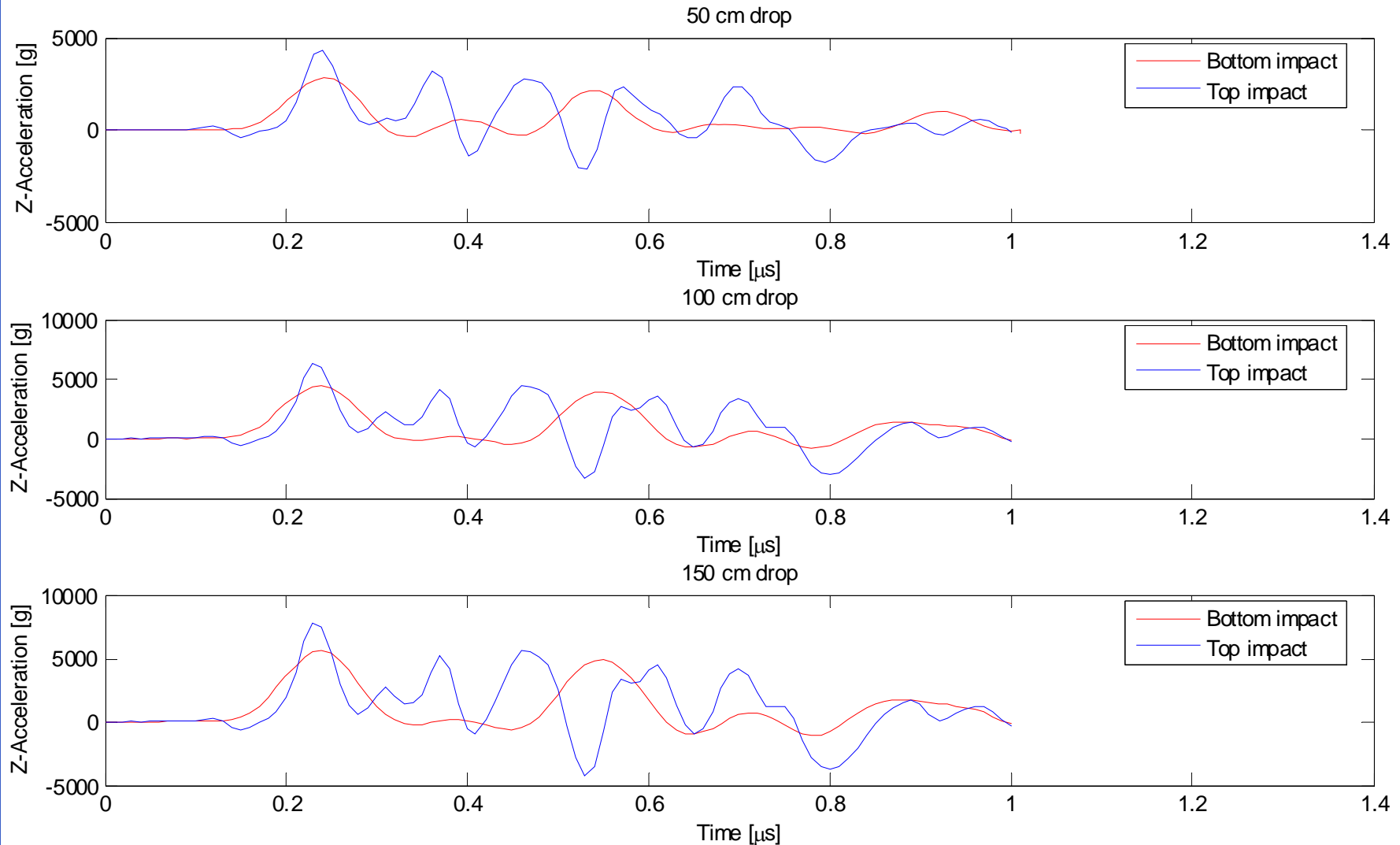
No failure observed
(IMEC)



Alberto Corigliano, Fabrizio Cacchione. Polimi

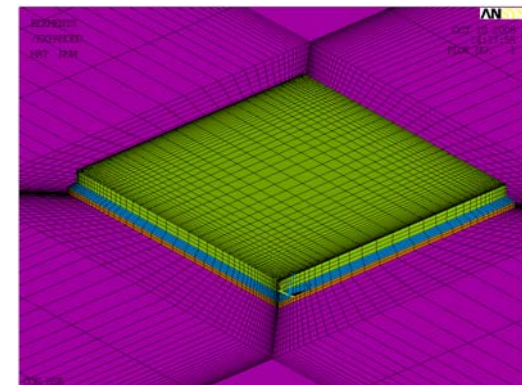
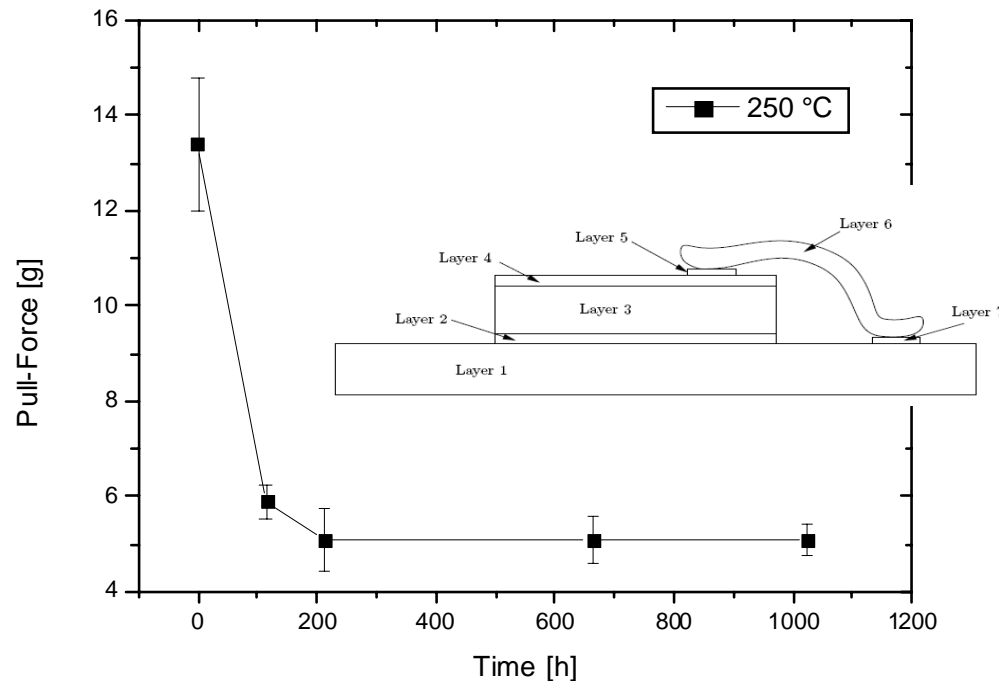


“bottom” and “top” z-acceleration history at different drop heights



- from RT to 250 or 300°C at pressures up to 100 bar (IMS)

Wire bond strength
 after storage at 250 °C



- simulations



HERMETICITY

Clause Pellet, IXL

Partners: IXL, IEF, BUTE, LETI, Tyndall, IMEC, Qinetiq, Polimi, IMT

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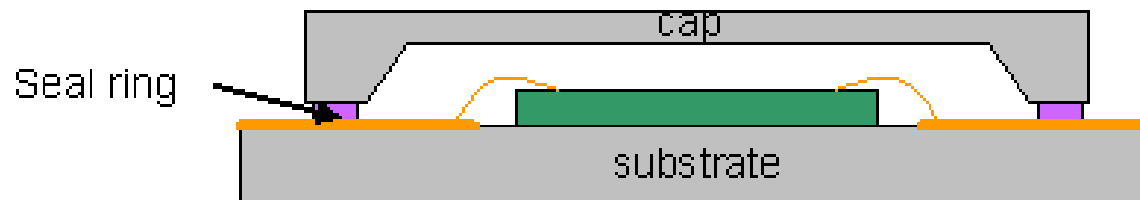
Aim : in-situ investigation of packaging hermeticity

Use a humidity microsensor as a device to demonstrate DfMM

Focus:

- wafer level packaging
- mainly polymer sealing ring

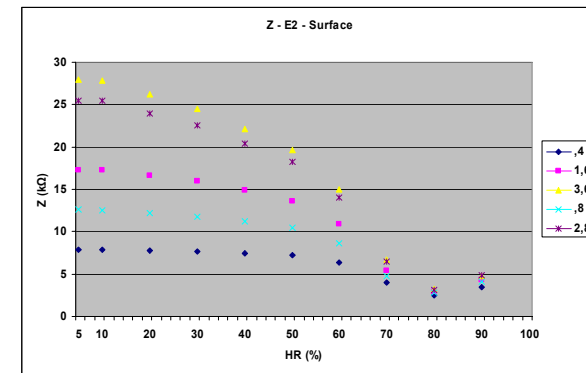
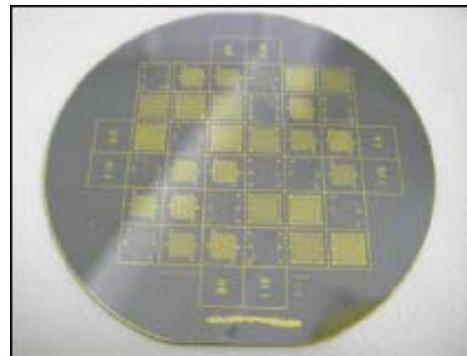
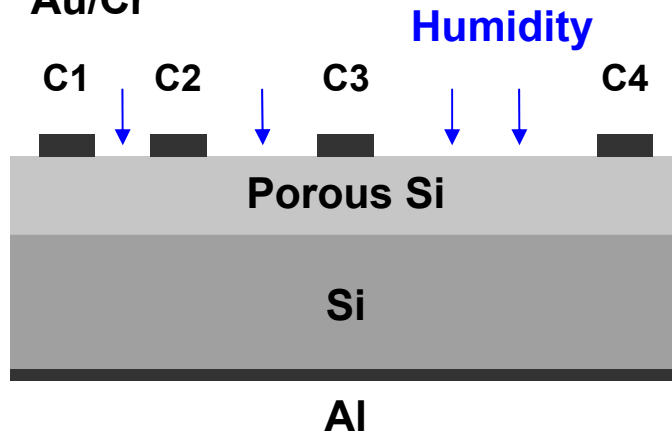
Gas diffusion simulations
In-situ monitoring of the atmosphere



- design, fabricate and test a humidity microsensor to electrically detect traces of humidity
- characterize, measure and simulate reliability and packaging issues for the integration of the microsensor within a package
- analyse reliability and packaging concerns of wafer level packaging technologies for MEMS devices
- investigate the reliability measurement and modelling challenges associated with humidity, hermeticity and wafer level packaging for MEMS
- define mechanisms for bringing together partner knowledge obtained from activities and projects undertaken during the first 2 years of the PATENT NoE (across all technical workpackages), to demonstrate DfMM via a specific demonstrator of direct industrial benefit.

- Resistive / capacitive structure

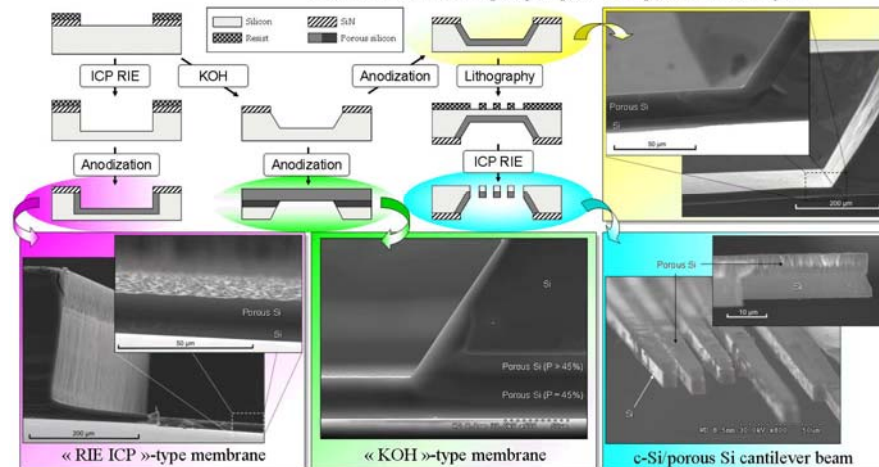
Contacts
Au/Cr



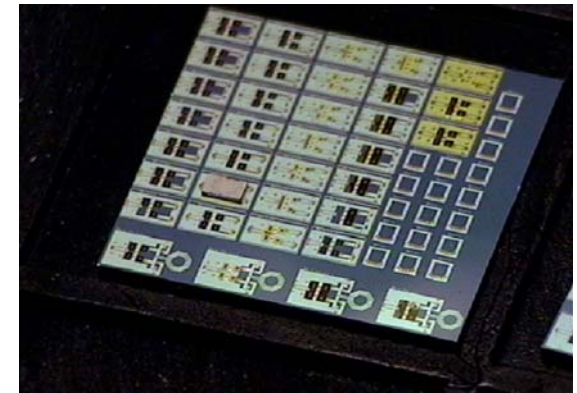
- Resonant structure

Fabrication processes

Two kinds of devices were fabricated: membranes and micro-cantilevers. All fabrication processes investigated are based on the fabrication of a monocrystalline silicon membrane followed by an electrochemical etching step to produce a porous silicon layer.

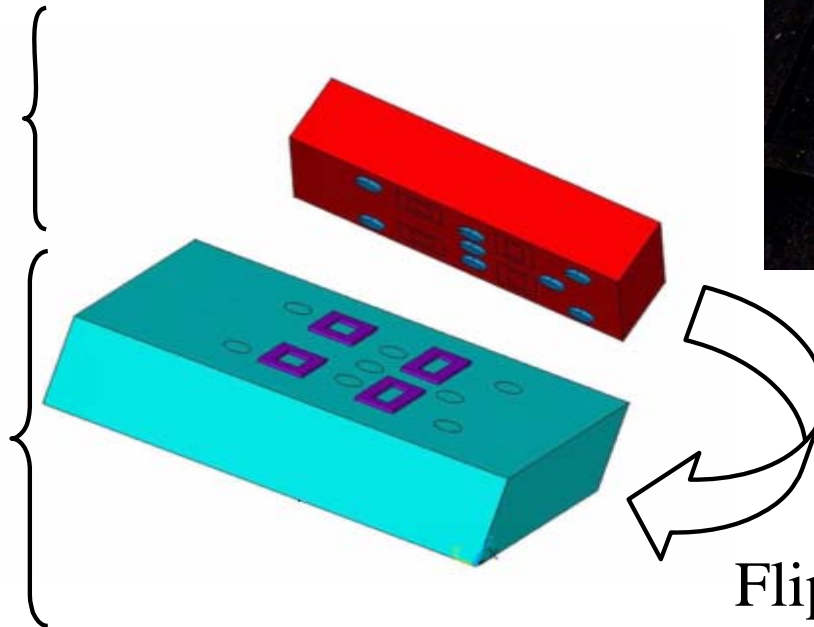


Integration of a die containing electro-mechanical component on a silicon substrate as a System in Package (SiP) solution



SAW filter
with contact

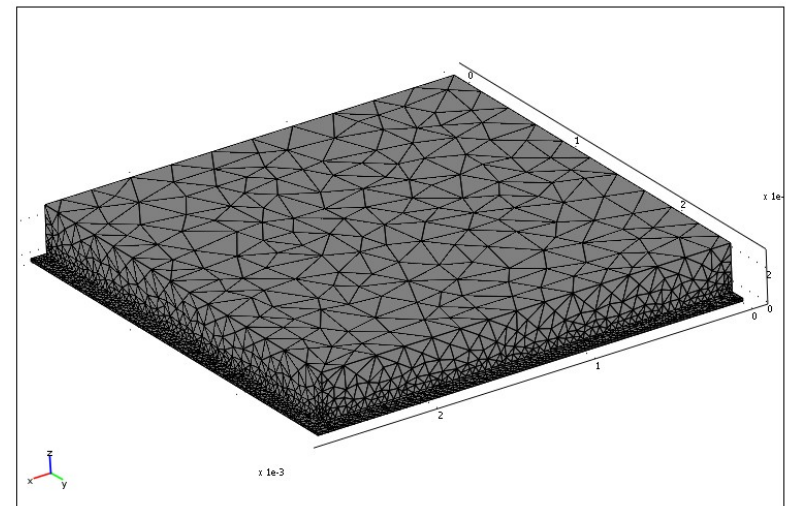
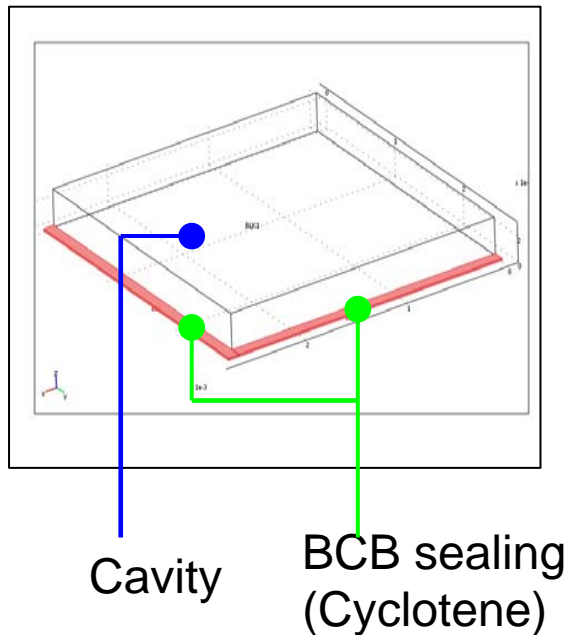
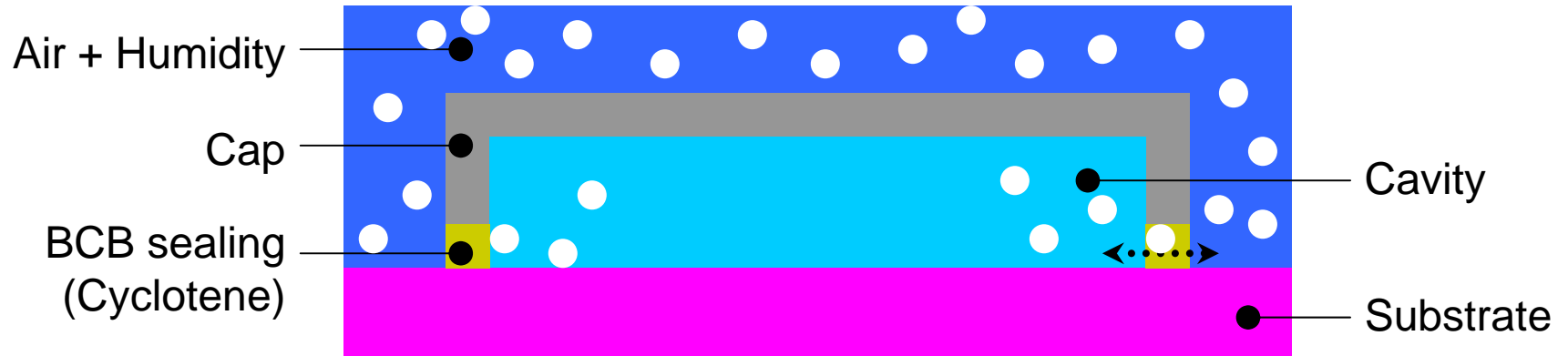
PICS
substrate with
polymer seal
rings



Flip-chip

PICS = Passive Integration Connecting Substrate

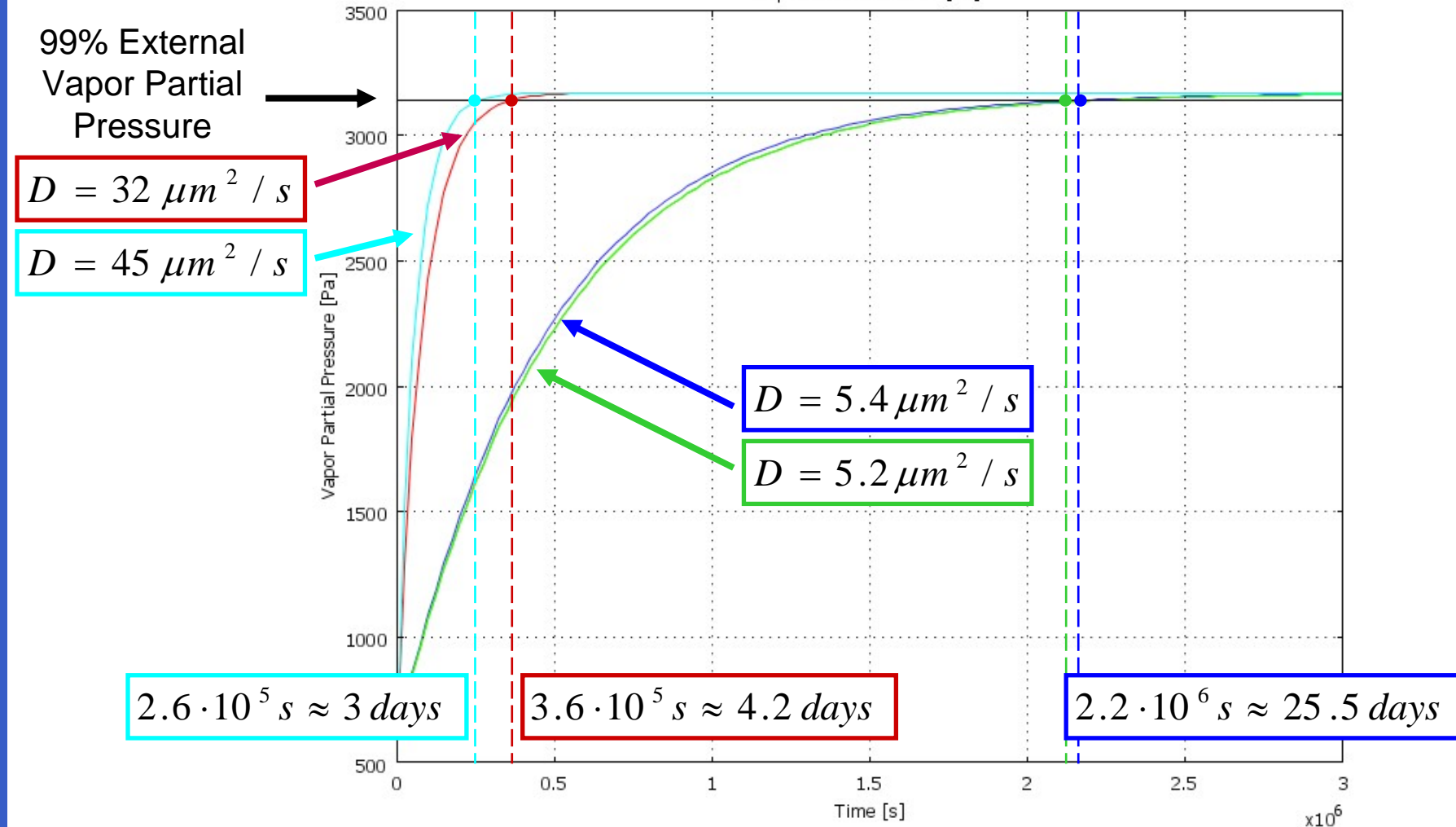
Alberto Corigliano, Livio Domenella. Polimi

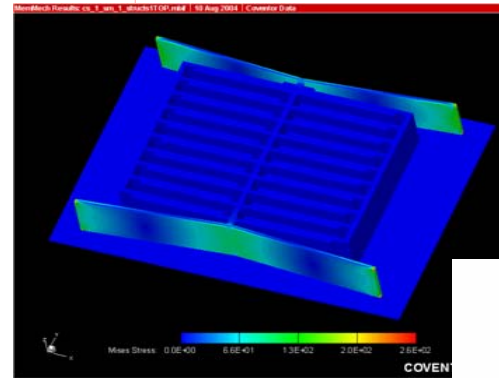
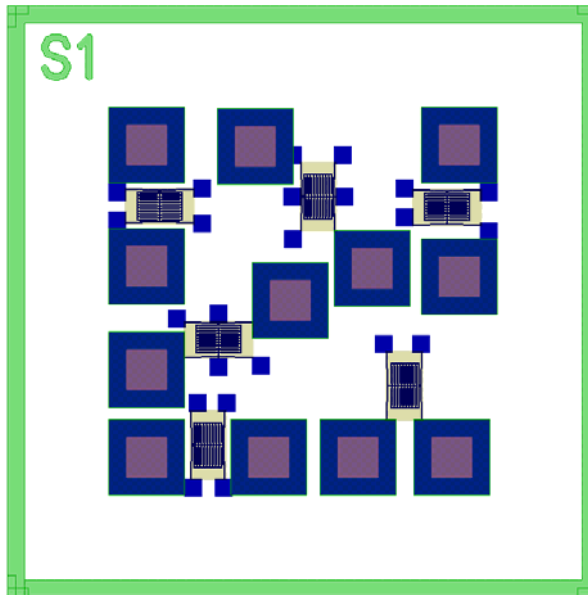


Partial pressure in the centre of the cavity

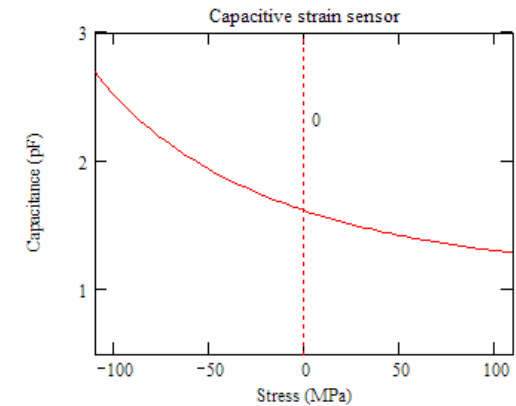
(External relative humidity: 100%)

Vapor Partial Pressure [Pa]



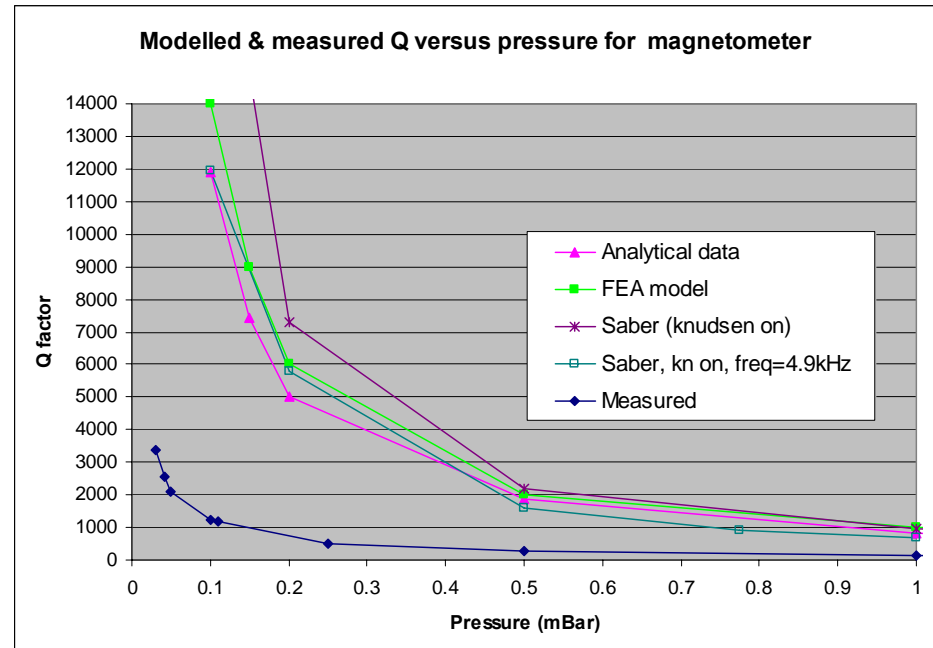
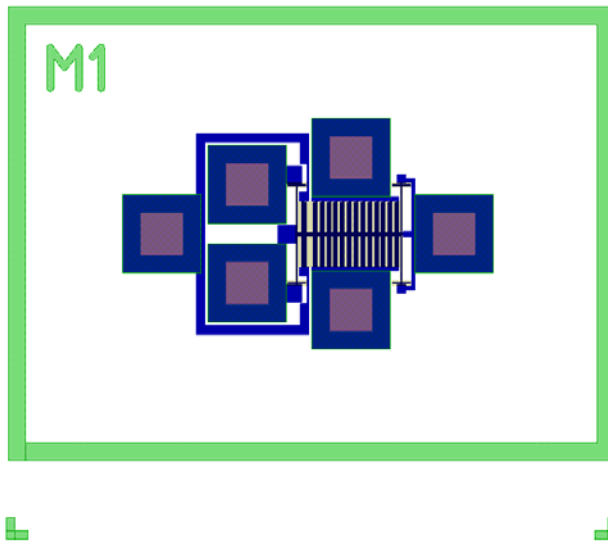


Qinetiq



- Based on a pair on bent beam devices,
 - uses a capacitive readout
- Four devices to measure compressive and tensile stress in two orthogonal directions, and two orthogonal devices for control.

Qinetiq



- Magnetometer - vibrating structure to assess the resultant cavity hermeticity/ vacuum
 - Using Q versus pressure relationship from trials with non-sealed device in vacuum chamber



Accelerometer

Precursor activities to possible
demonstrator project for PATENT-DfMM
NoE

Alan Brown

QinetiQ

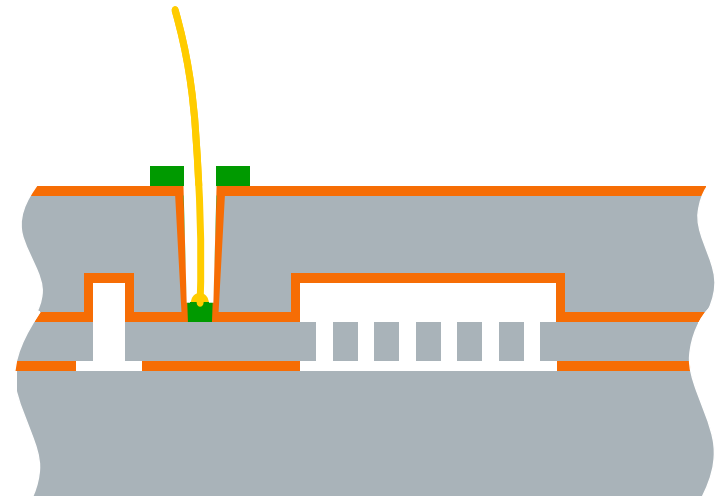
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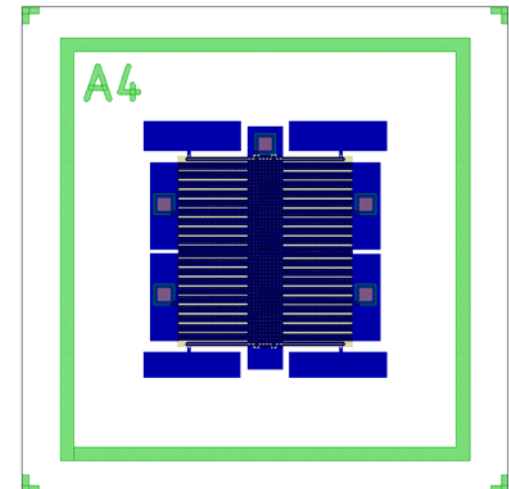
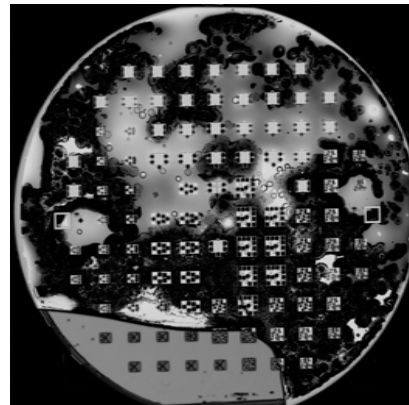
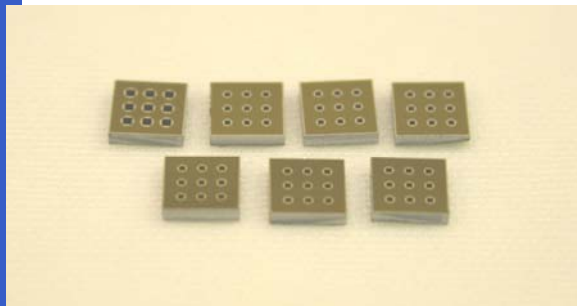
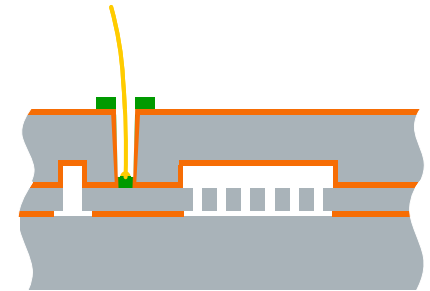
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- ❑ **Scope:** to demonstrate a testable, reliable low cost packaged accelerometer.
- ❑ The activity intends to build on previous work within PATENT.
- ❑ Based on the outcome a detailed proposal for the proposed demonstrator activity will be prepared for consideration as part of the call process for 2007 activities.

- QinetiQ to conduct a small precursor study on low cost packaging of SOI accelerometer devices.
 - A number of packaging options will be considered/ including, Chip on Board Assembly/Packaging and Wafer level packaging
 - Packaging trials will be conducted, and
 - if successful, samples will be supplied to the partners for initial reliability screening



- Limitations of wire bonding in vias studied
 - using dedicated bonding tools (demonstrated for 300 micron vias)
 - With involvement of the tool company
 - With use of thinned wafers
- Study of wafer to wafer bonding
 - Test samples being fabricated
 - Tests are ongoing



- low cost (polymer intermediate bonding layer & Chip on Board mounting)
 - Full hermeticity not required for many applications

- Aim to pull together work on
 - CoB packaging
 - SU-8 bonding & associated reliability studies (or BCB)
 - Round robin modelling/ Die attach for stress sensitive devices
 - Accelerated testing study
 - SOI reliability work
 - Motionless testing at wafer level & Bias superposition

Reliability for MEMS is | **MEMS's best friend**